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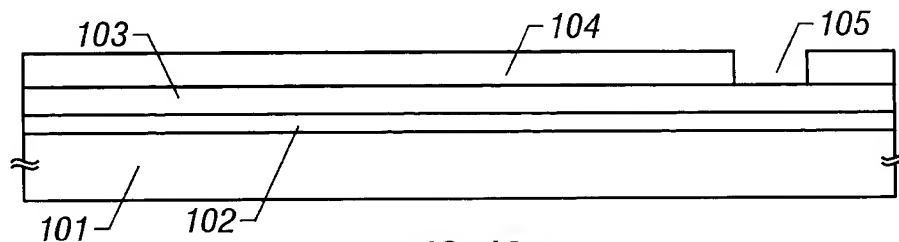


FIG. 1A

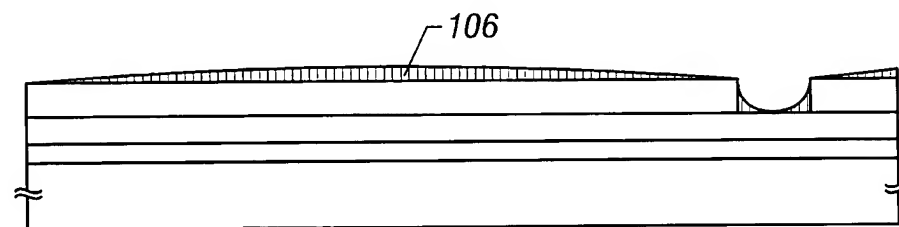


FIG. 1B

HEAT TREATMENT FOR CRYSTALLIZATION

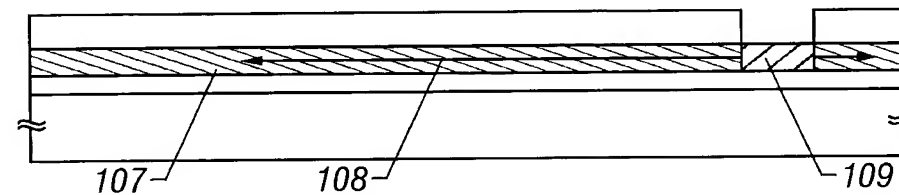


FIG. 1C

HEAT TREATMENT IN ATMOSPHERE CONTAINING HALOGEN ELEMENT

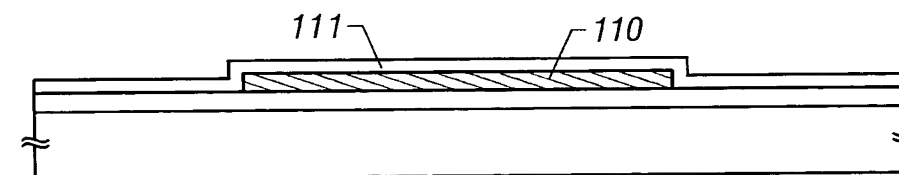


FIG. 1D

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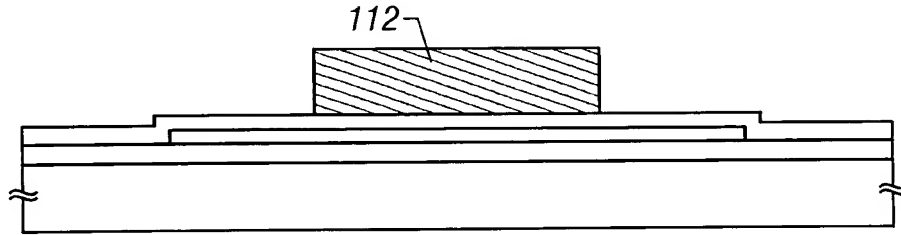


FIG. 2A

IMPURITY ION IMPLANTATION

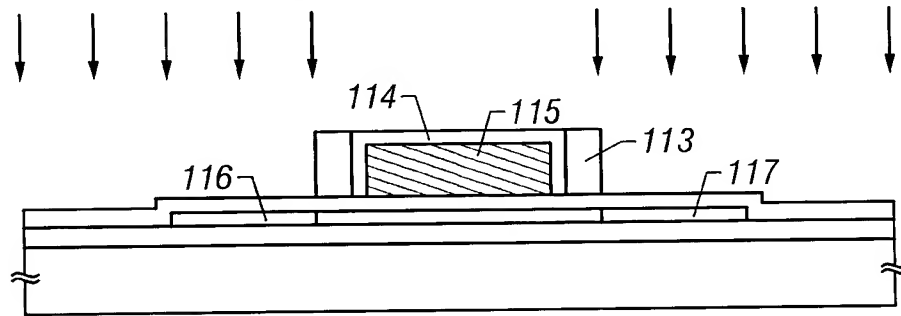


FIG. 2B

IMPURITY ION IMPLANTATION

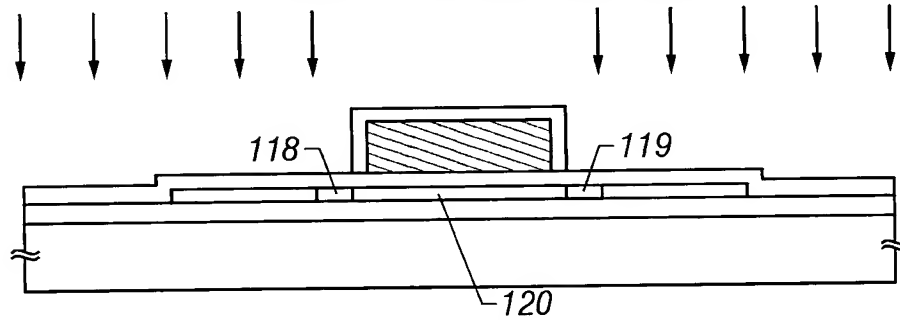


FIG. 2C

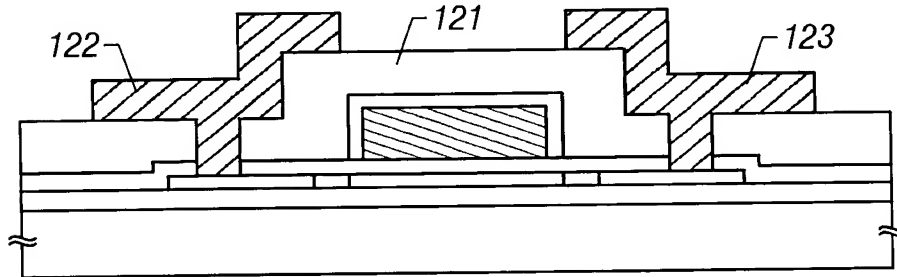


FIG. 2D

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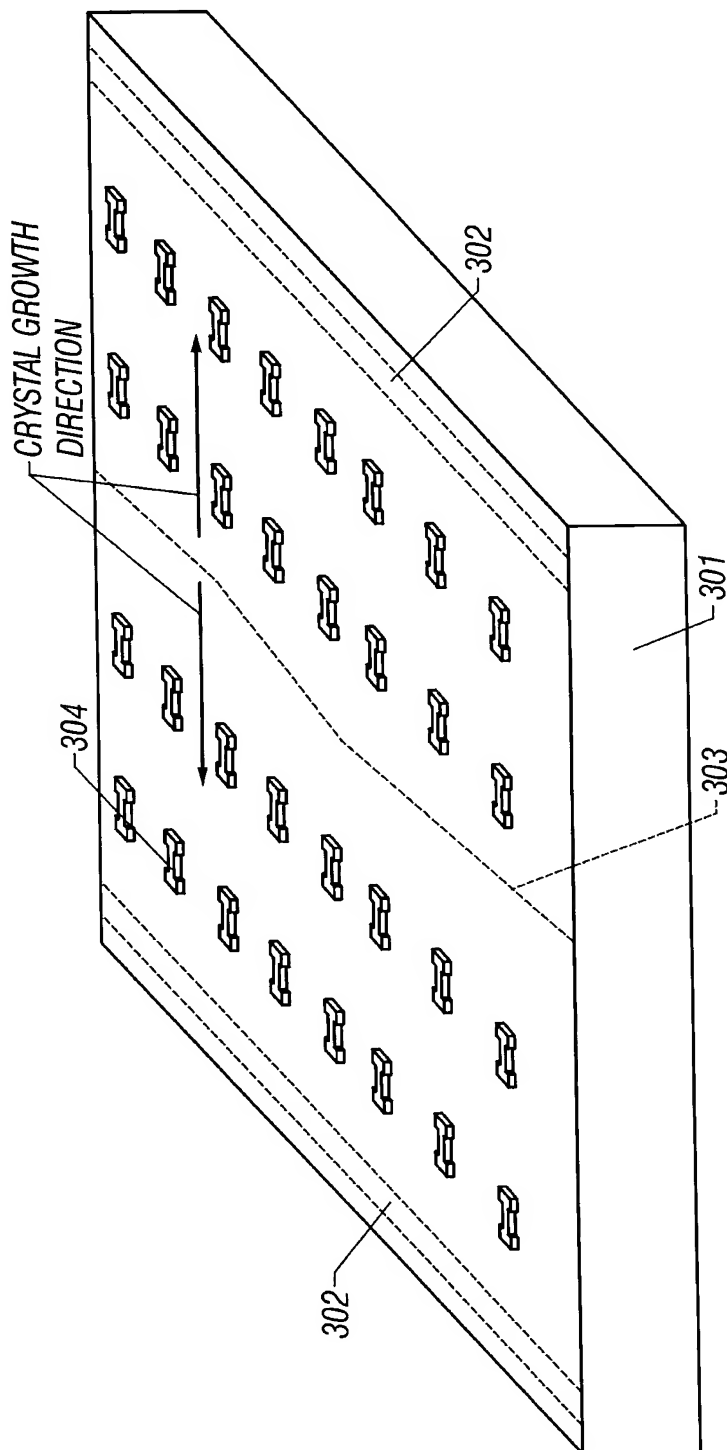


FIG. 3

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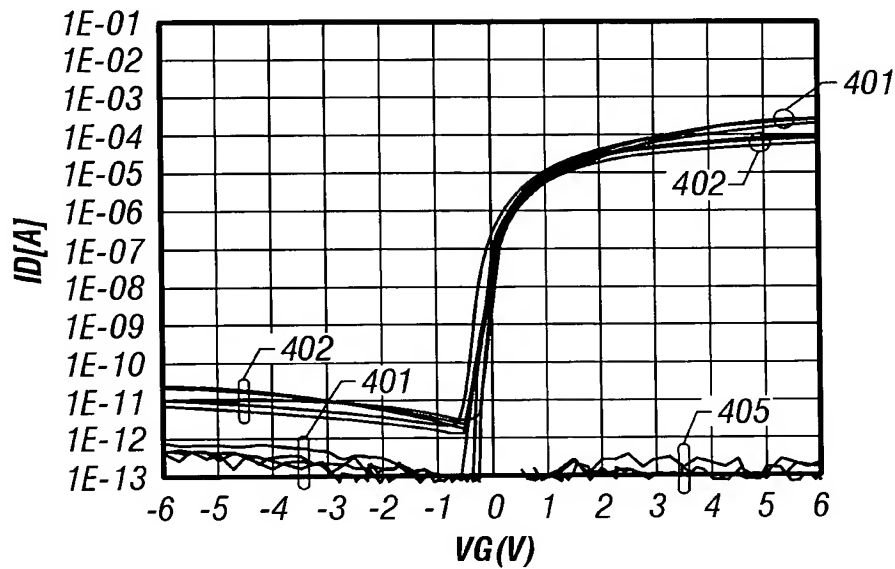


FIG. 4A

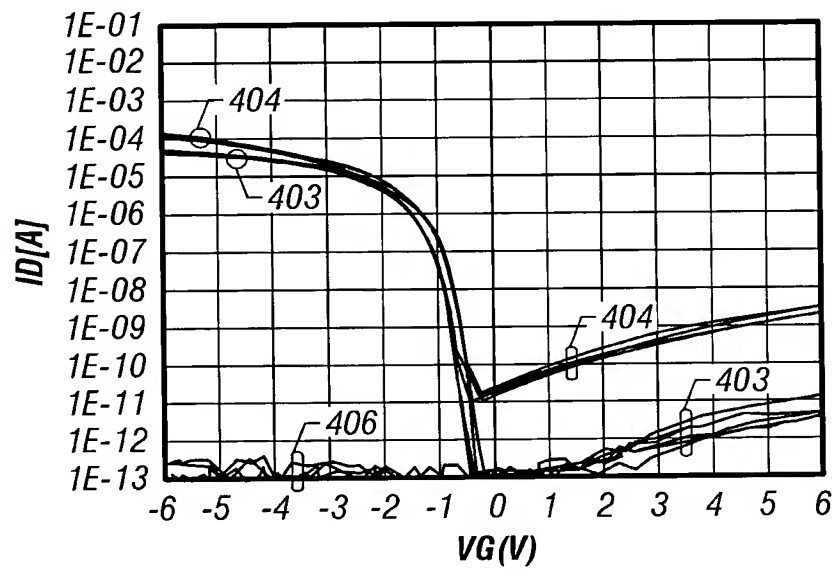


FIG. 4B

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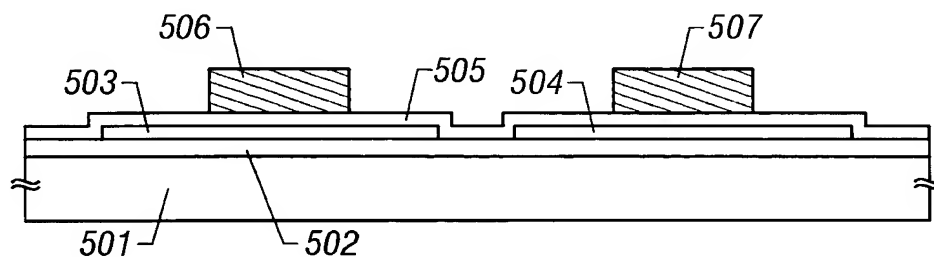


FIG. 5A

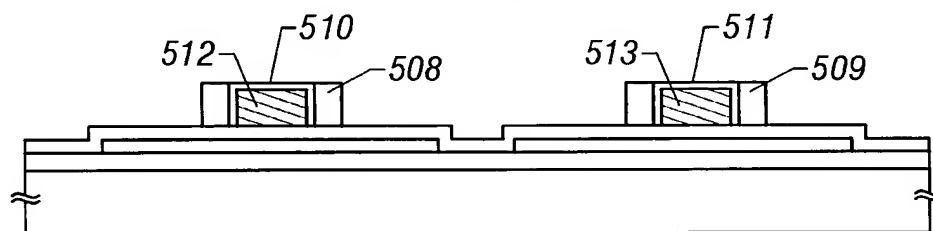


FIG. 5B

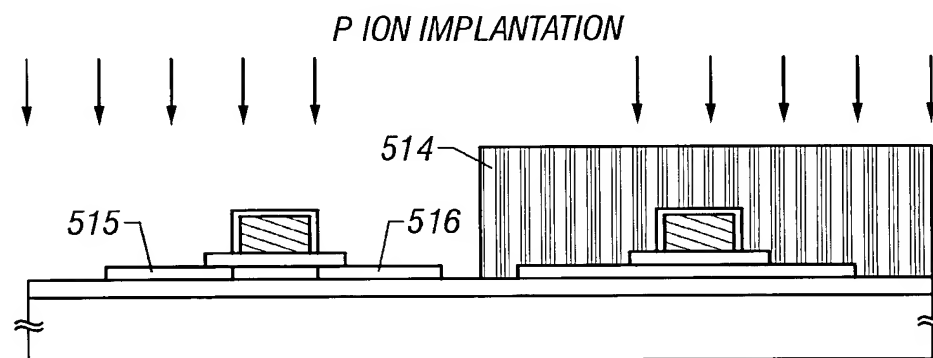
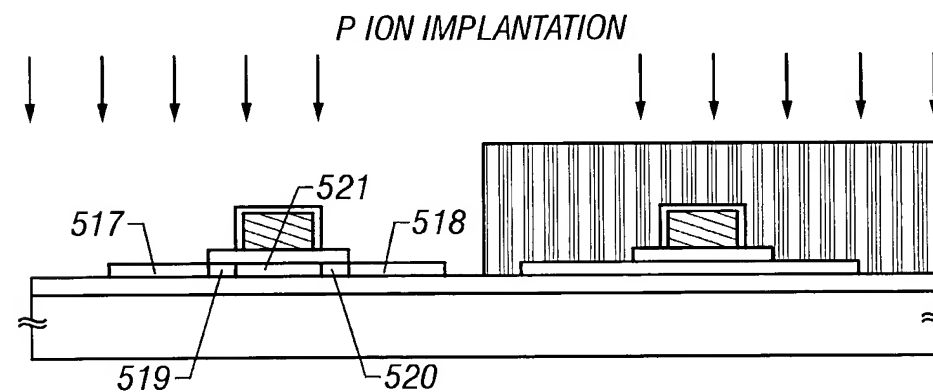


FIG. 5C



N-CHANNEL TYPE TFT

P-CHANNEL TYPE TFT

FIG. 5D

B ION IMPLANTATION



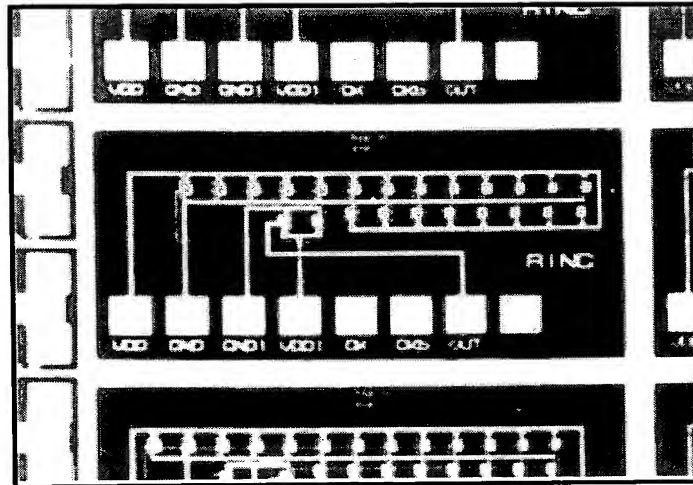
B ION IMPLANTATION



P-CHANNEL TYPE TFT

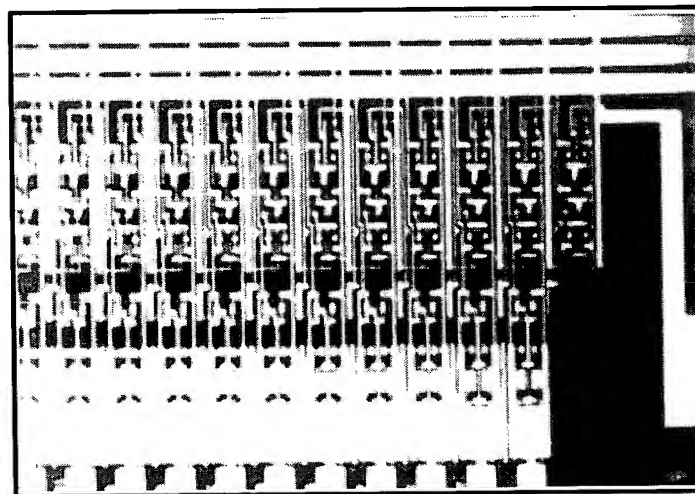
FIG. 6C

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150 μ m

FIG. 7A



150 μ m

FIG. 7B

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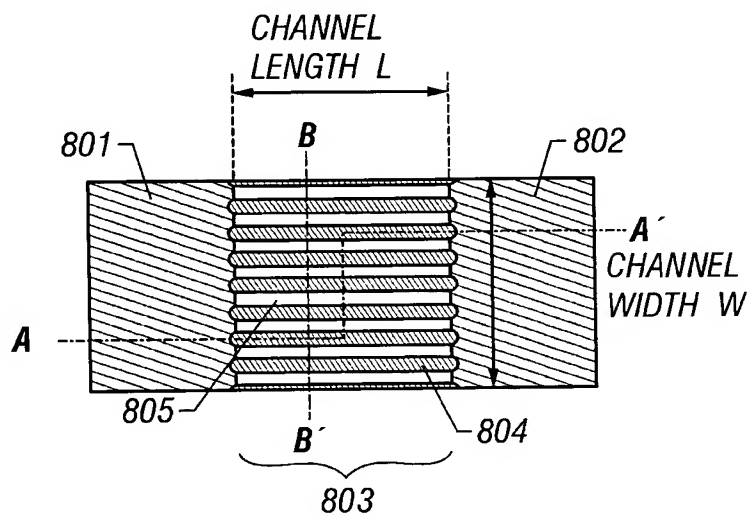


FIG. 8A

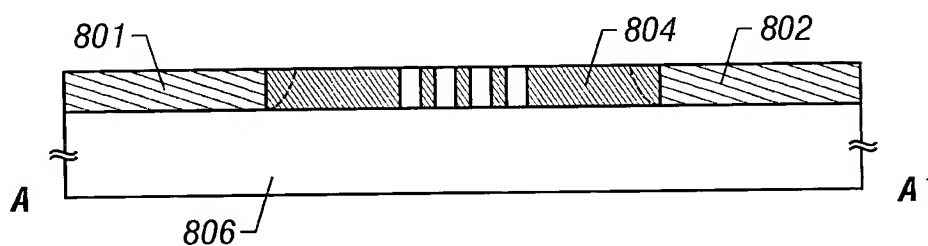


FIG. 8B

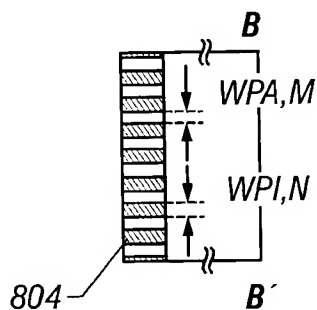


FIG. 8C

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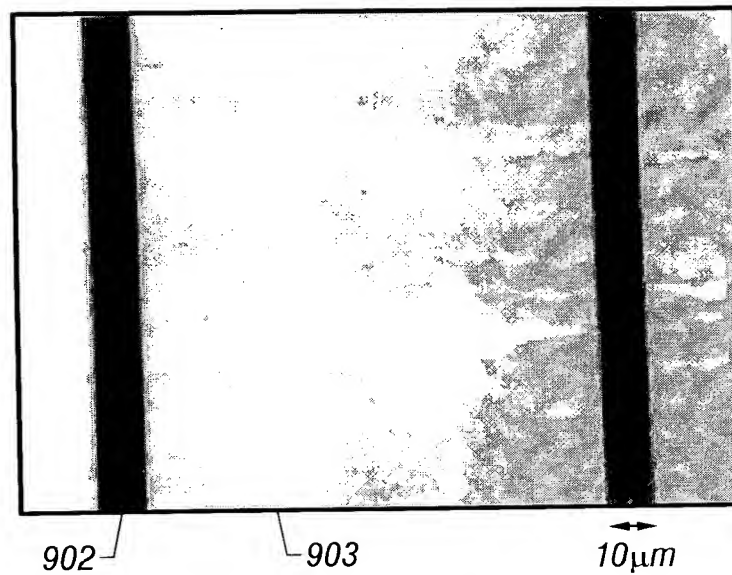


FIG. 9

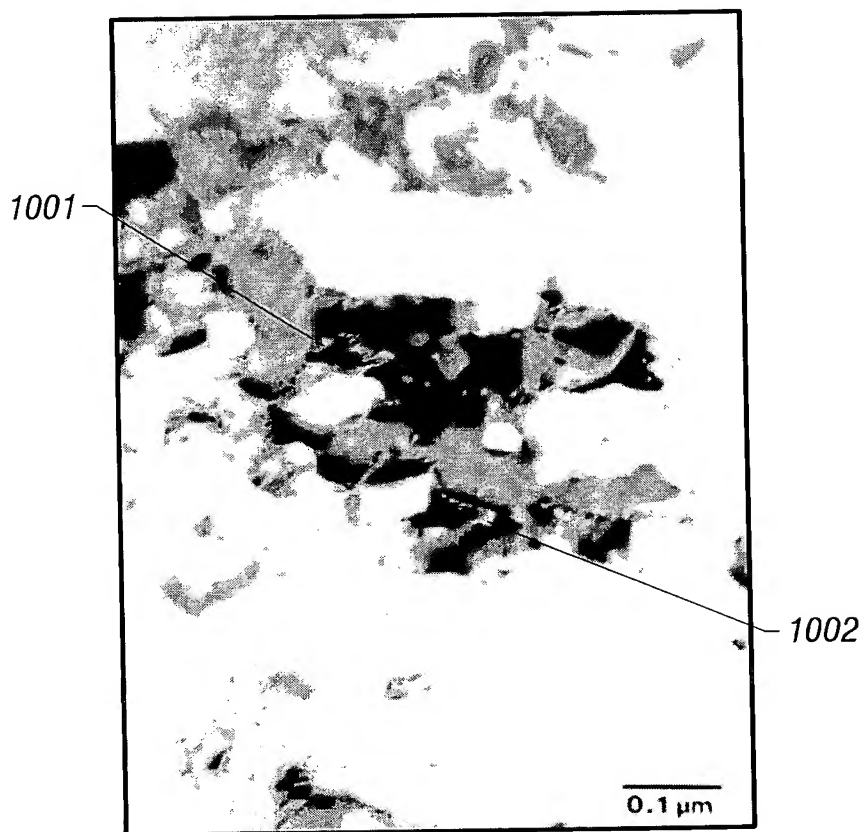


FIG. 10

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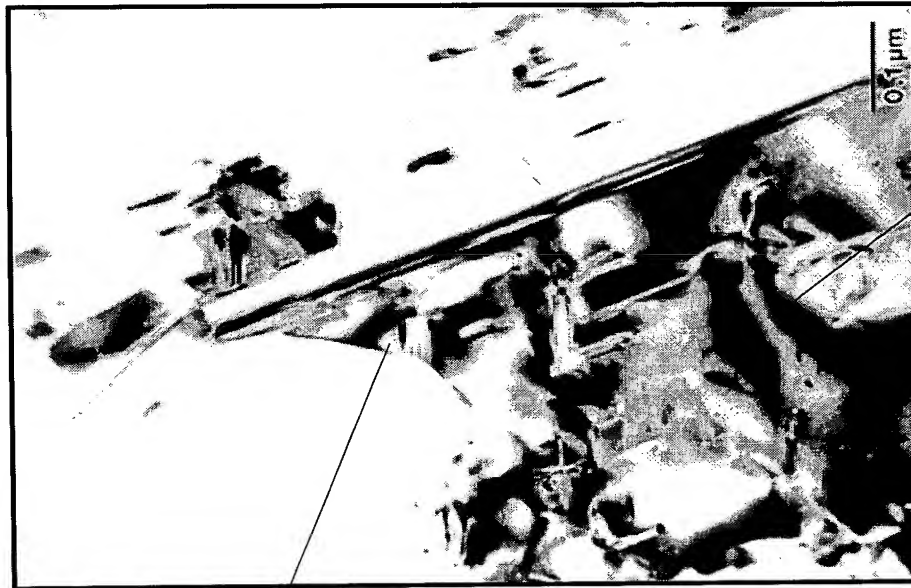


FIG. 12



FIG. 11

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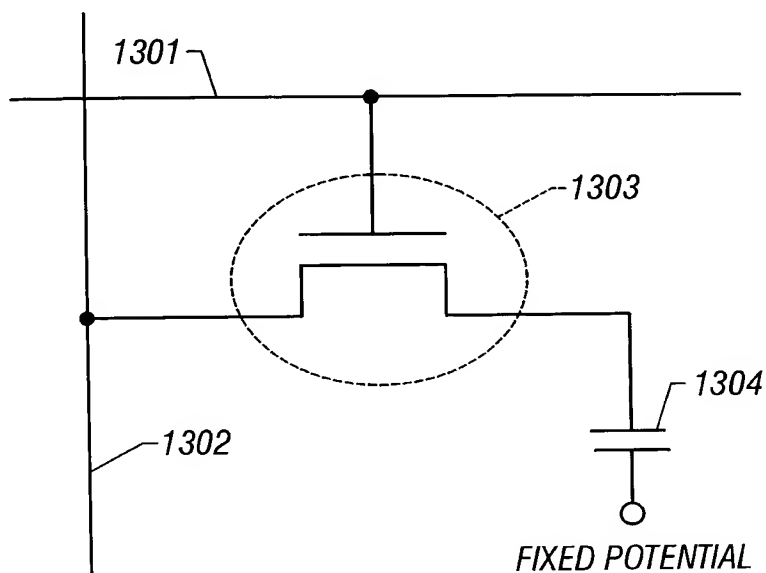


FIG. 13A

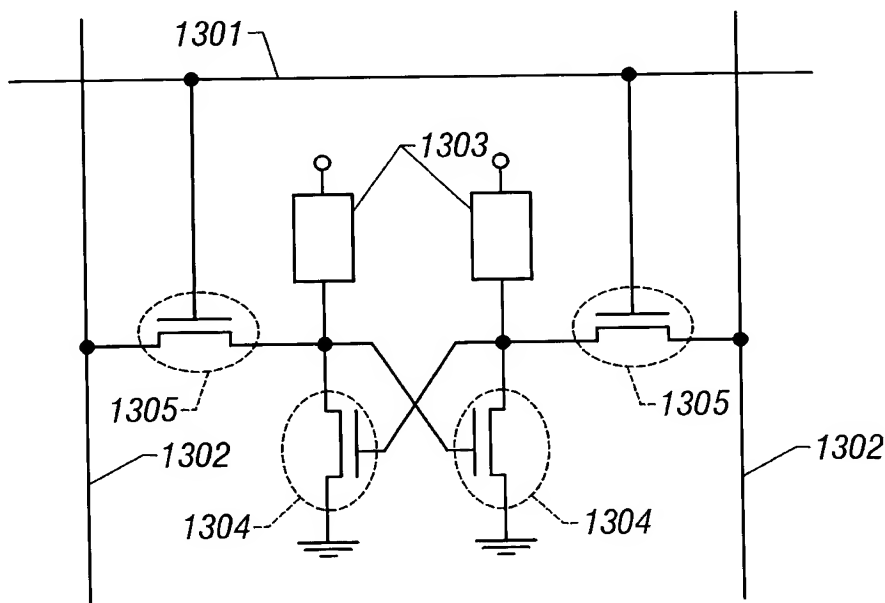


FIG. 13B

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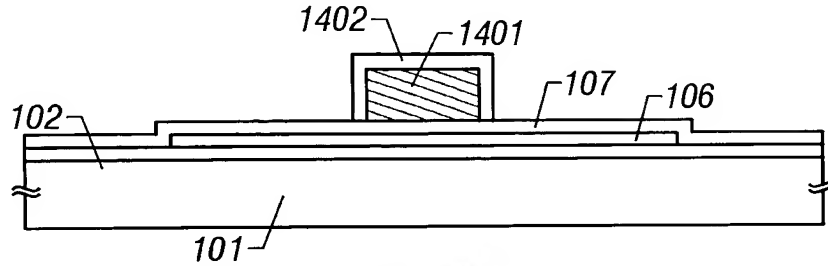


FIG. 14A

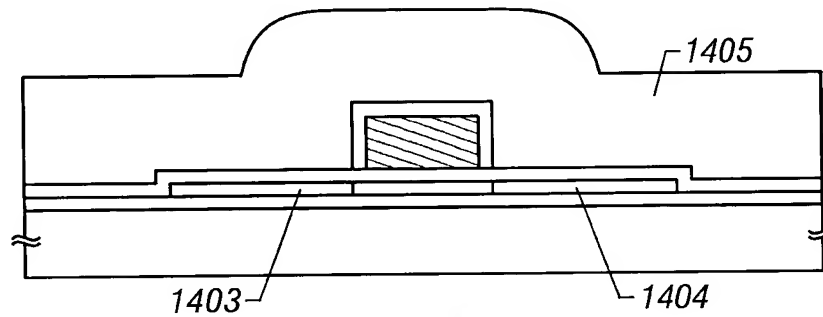


FIG. 14B

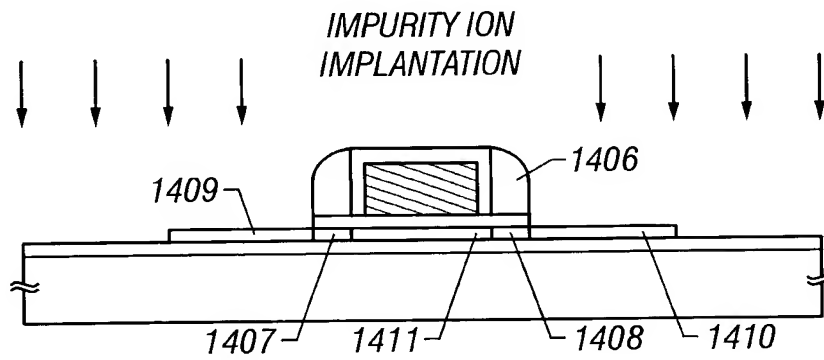


FIG. 14C

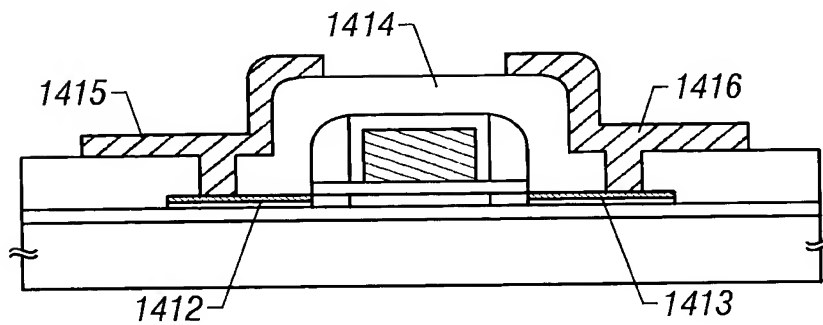


FIG. 14D

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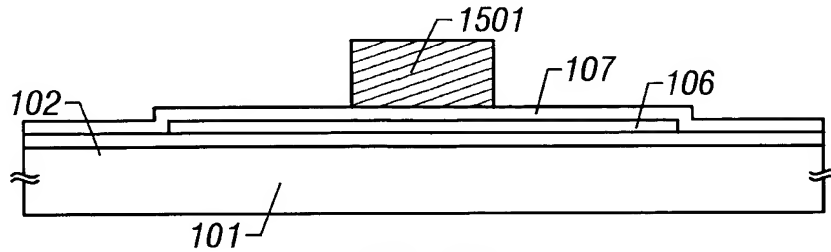


FIG. 15A

IMPURITY ION
IMPLANTATION

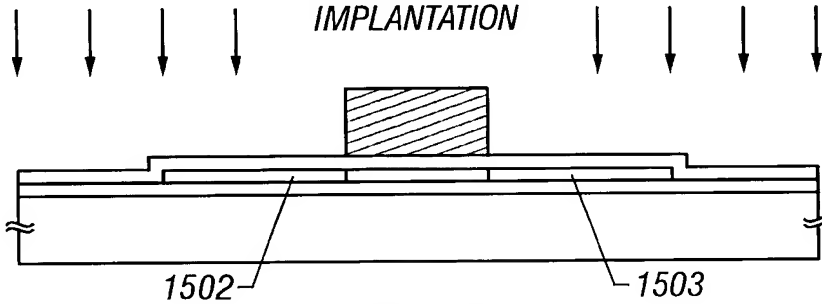


FIG. 15B

IMPURITY ION
IMPLANTATION

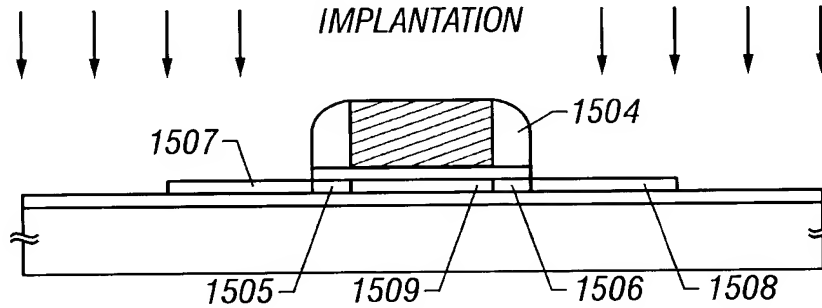


FIG. 15C

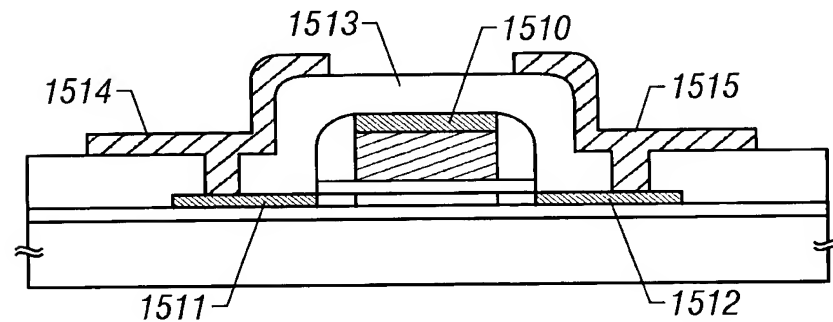


FIG. 15D

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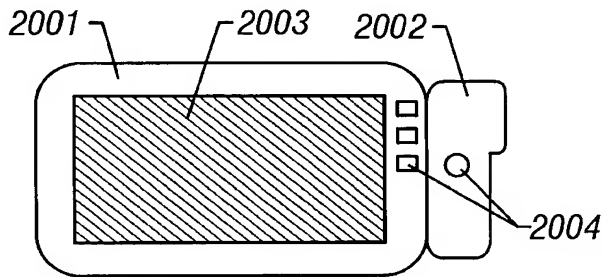


FIG. 16A

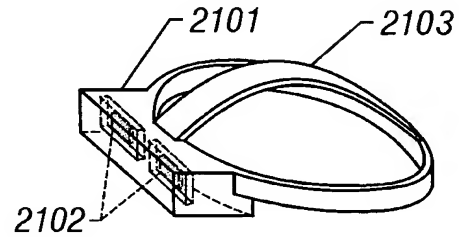


FIG. 16B

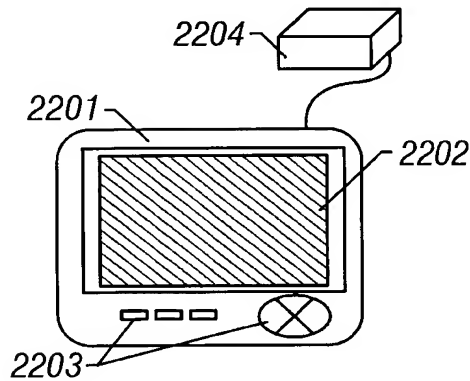


FIG. 16C

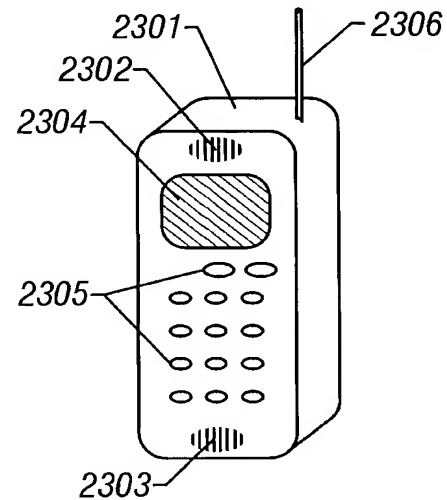


FIG. 16D

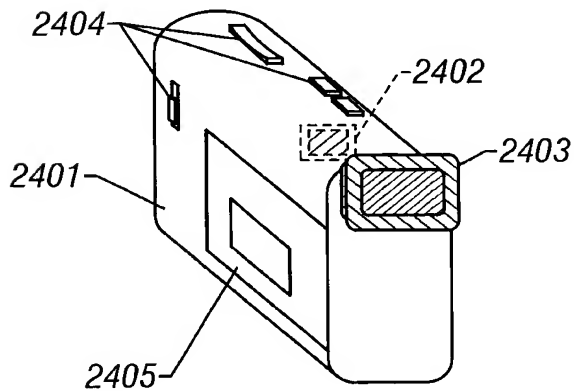


FIG. 16E

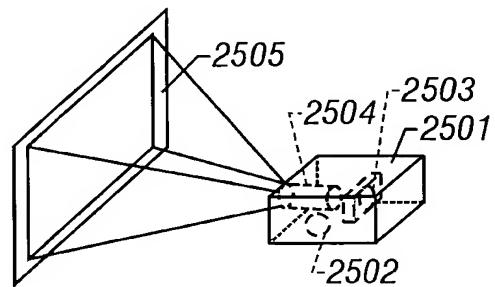


FIG. 16F